

Customer No.: 31561
Application No.: 10/709,717
Docket No.: 13004-US-PA

AMENDMENTS

To the Claims:

Claim 1. (currently amended) A fluid ejection device suitable for an ink-jet printer, comprising:

a substrate, having an orifice;

a beam, disposed over the substrate, the beam having a fixed portion and a cantilever portion, wherein the cantilever portion is disposed over the orifice; and

an activation pad, disposed between the cantilever portion of the beam and the substrate, wherein the activation pad are disposed apart from the beam; and

a stopper, disposed on the cantilever portion of the beam and aligned to the orifice of the substrate.

Claim 2. (cancelled)

Claim 3. (currently amended) The fluid ejection device of claim 12, wherein a dimension of the stopper is larger than that of the orifice.

Claim 4. (original) The fluid ejection device of claim 1, wherein the fixed portion of the beam is a collar structure disposed on the substrate for supporting the cantilever portion.

Claim 5. (original) The fluid ejection device of claim 1, further comprising an encapsulation structure covering the substrate for encapsulating the beam and the activation pad.

Claim 6. (withdrawn) A method of fabricating a fluid ejection device, comprising:

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providing a substrate;
forming an activation pad over the substrate;
forming a patterned sacrificial layer over the substrate, covering the activation pad,
wherein the patterned sacrificial layer comprises an opening exposing a portion of the
substrate there-within;
forming a patterned mold layer over the sacrificial layer, wherein the patterned
mold layer comprises a trench exposing the opening;
forming a first conductive layer in the opening and the trench;
forming a hole from a backside of the substrate; and
removing the patterned sacrificial layer and the mold layer, wherein the first
conductive layer forms a beam structure.

Claim 7. (withdrawn) The method of fabricating a fluid ejection device of claim 6,
wherein the step of forming the activation pad on the substrate comprises:

forming an oxide layer over the substrate;
forming a second conductive layer over the oxide layer; and
etching the second conductive layer and the mold layer to form the activation pad.

Claim 8. (withdrawn) The method of fabricating a fluid ejection device of claim 6,
wherein the patterned sacrificial layer further comprises an indentation.

Claim 9. (withdrawn) The manufacturing method of a fluid ejection device of
claim 8, wherein, after removing the patterned sacrificial layer and the mold layer, the

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first conductive layer comprises a stopper connecting thereto that correspond to the indentation.

Claim 10. (withdrawn) The method of fabricating a fluid ejection device of claim 6, further comprising a step of depositing a seed layer over the patterned sacrificial layer before forming the first conductive layer in the opening and the trench.

Claim 11. (withdrawn) The method of fabricating a fluid ejection device of claim 6, wherein the step of forming the hole from the backside of the substrate comprises:

forming a patterned mask layer over the backside of the substrate for exposing a portion of the backside of the substrate; and

etching the exposed portion of the backside of the substrate by using the mask layer as an etching mask to form the hole.

Claim 12. (withdrawn) The method of fabricating a fluid ejection device of claim 11, further comprising a step of simultaneously removing the patterned mask layer, the sacrificial layer and the mold layer.

Claim 13. (withdrawn) The method of fabricating a fluid ejection device of claim 6, wherein the step of forming the hole from the backside of the substrate comprises:

forming a first patterned mask layer over the backside of the substrate for exposing a portion of the backside of the substrate;

etching the exposed substrate using the first patterned mask layer as an etching mask to form a notch;

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forming a second patterned mask layer on the backside of the substrate for
exposing a portion of a bottom of the notch; and
etching the exposed portion of the bottom of the notch using the second patterned
mask layer as an etching mask to form the hole.

Claim 14. (withdrawn) The method of fabricating a fluid ejection device of claim
13, wherein the patterned sacrificial layer, first and second patterned mask layer, and the
mold layer are removed simultaneously.

Claim 15. (withdrawn) The method of fabricating a fluid ejection device of claim
6, wherein the step of forming the hole from the backside of the substrate comprises:

forming a first patterned mask layer over the backside of the substrate for
exposing a portion of the backside of the substrate;
etching the exposed portion of the backside of the substrate using the first mask
layer as an etching mask to form a notch;
removing the first patterned mask layer;
forming a second patterned mask layer over the backside of the substrate for
exposing a portion of a bottom of the notch; and
etching the exposed portion of the bottom of the notch using the second patterned
mask layer as an etching mask to form the hole.

Claim 16. (withdrawn) The method of fabricating a fluid ejection device of claim
15, wherein the sacrificial layer, the first and second patterned mask layers, and the mold
layer are removed simultaneously.

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Claim 17. (withdrawn) The method of fabricating a fluid ejection device of claim 11, further comprising a step of encapsulating the substrate for protecting the activation pad and the beam after removing the sacrificial layer and the mold layer.

Claim 18. (currently amended) A method of operating a fluid ejection device, comprising:

providing the fluid ejection device of claim 1;

providing a fluid;

filling the fluid into the fluid ejection device;

wherein when a voltage is applied to the activation pad resulting in a voltage difference occurring between the activation pad and the beam, the cantilever portion of the beam is pulled down from an initial position toward the orifice of the substrate resulting in the stopper sticking to the orifice for ejecting the fluid out of the orifice; and

wherein when the voltage applied to the activation pad is removed, the cantilever portion of the beam gradually moves away from the orifice.

Claim 19. (original) The method of operating a fluid ejection device of claim 18, wherein when the voltage applied to the activation pad is removed, the cantilever portion of the beam gradually moves away from the orifice.

Claim 20. (original) The method of operating a fluid ejection device of claim 18, wherein when the voltage is applied to the activation pad, the cantilever portion of the beam is pulled down for, contacting the orifice of the substrate and thereby ejecting the fluid from the orifice.